

Customer Number 22,852
Attorney Docket No. 03180.0356

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Takashi SATO et al.)
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Application No.: 10/781,652) Group Art Unit: 2851
)
Filed: February 20, 2004)
)
For: LITHOGRAPHY SIMULATION)
METHOD, MASK PATTERN)
CORRECTION METHOD, AND)
SUBSTRATE TOPOGRAPHY)
CORRECTION METHOD)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

CLAIM FOR PRIORITY

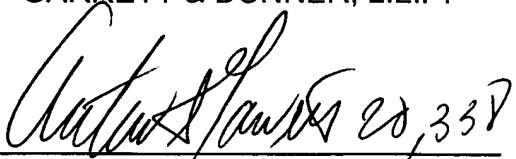
Under the provisions of Section 119 of 35 U.S.C., applicants hereby claim the benefit of the filing date of Japanese Patent Application No. 2003-044443, for the above identified United States Patent Application.

In support of applicants claim for priority, filed herewith is one certified copy of the above.

Respectfully submitted,

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GARRETT & DUNNER, L.L.P.

Dated: July 12, 2004

By: 
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